

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

(Case No. 219.005-C1)

In the Application of: Yamada et al.

Serial No: 10/790,276

Filed: March 1, 2004

Title: Production Managing System of Semiconductor)

**Device** 

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Group

Art Unit: 2825

Examiner:

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on June 25, 2004

(person signing this certificate)

Signature

## THIRD INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Submitted herewith are two (2) sheets of a modified Form PTO-1449. A copy of each document cited on the attached Form PTO-1449 is also submitted.

It is respectfully requested that the Examiner make his/her consideration of these documents formally of record with the initial Office Action.

Date: June 25, 2004

Respectfully submitted,

Neil A. Steinberg Reg. No. 34,735 650-968-8079 Sheet 1 of 2

ATTY. DOCKET NO. SERIAL NUMBER

219.005-C1-US 10/790,276

EPARTMENT OF COMMERCE APPLICANT(S)

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

Yamada et al.
FILING DATE

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

LING DATE GROUP ART UNIT

March 1, 2004 2825

## U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO	
	03-205573	9/1991	Japan				
	04-062857	2/1992	Japan				
	06-273297	9/1994	Japan				
	07-066172	3/1995	Japan				
	08-005528	1/1996	Japan			Υ	
	08-313244	11/1996	Japan				
	09-061142	3/1997	Japan			Υ	
	10-281746	10/1998	Japan				
	10-300450	11/1998	Japan				
	11-026343	1/1999	Japan				
	2000-164715	6/2000	Japan				
	2000-180143	6/2000	Japan				
	2000-124276	4/2000	Japan				
	2000-174077	6/2000	Japan				

 OTHER	DOCUMENTS	(Including	Author,	Title,	Date,	Pertinent	Pages,	Etc.)
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DATE CONSIDERED

EXAMINER: Initial citation if reference was considered. Draw line through citation if not in conformance to MPEP 609 and not considered. Include copy of this form with next communication to applicant.

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PTO-1449 (Modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT BY APPLICANT			219.005-C1-US	10/790,2	76					
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EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	YE	s/NO			
	50-63990	5/1975	Japan			Υ				
	57-6310	1/1982	Japan	<u> </u>		Υ				
	62-19707	1/1987	Japan			Υ				
	63-9807	1/1988	Japan							
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			Author, Title, Date, Pe							
	"An In-Line Contac al., IEEE 1999, Doo	t and Via Hole In: c. No. 0-7803-54	spection Method Using Electron E 13-3/99/, available from <u>http://www</u>	Beam Compensations.fabsol.com/us/ima	n Current", ages/library	Yamac <u>/21.pdf</u>	la et			
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